

wherein said vessel incorporates at least one adsorbent capable of adsorbing on organic substance, and said adsorbent is mounted detachably, and wherein said at least one adsorbent is a material with a surface having an Si-F bond.

~~6~~ **10. (Amended)** A method of manufacturing a semiconductor device wherein a semiconductor substrate is stored in a stock/transfer vessel incorporating at least one adsorbent capable of adsorbing an organic substance during an operation wait time between respective steps of manufacturing said semiconductor device, said adsorbent being mounted detachably, and wherein said at least one adsorbent is selected to be a material with a surface having an Si-F bond.